



UiO : **Department of Informatics**
University of Oslo

INF5442 – Image Sensor Circuits and Systems

Lecture 2 – Photon detection and pixel circuits

1-September-2014



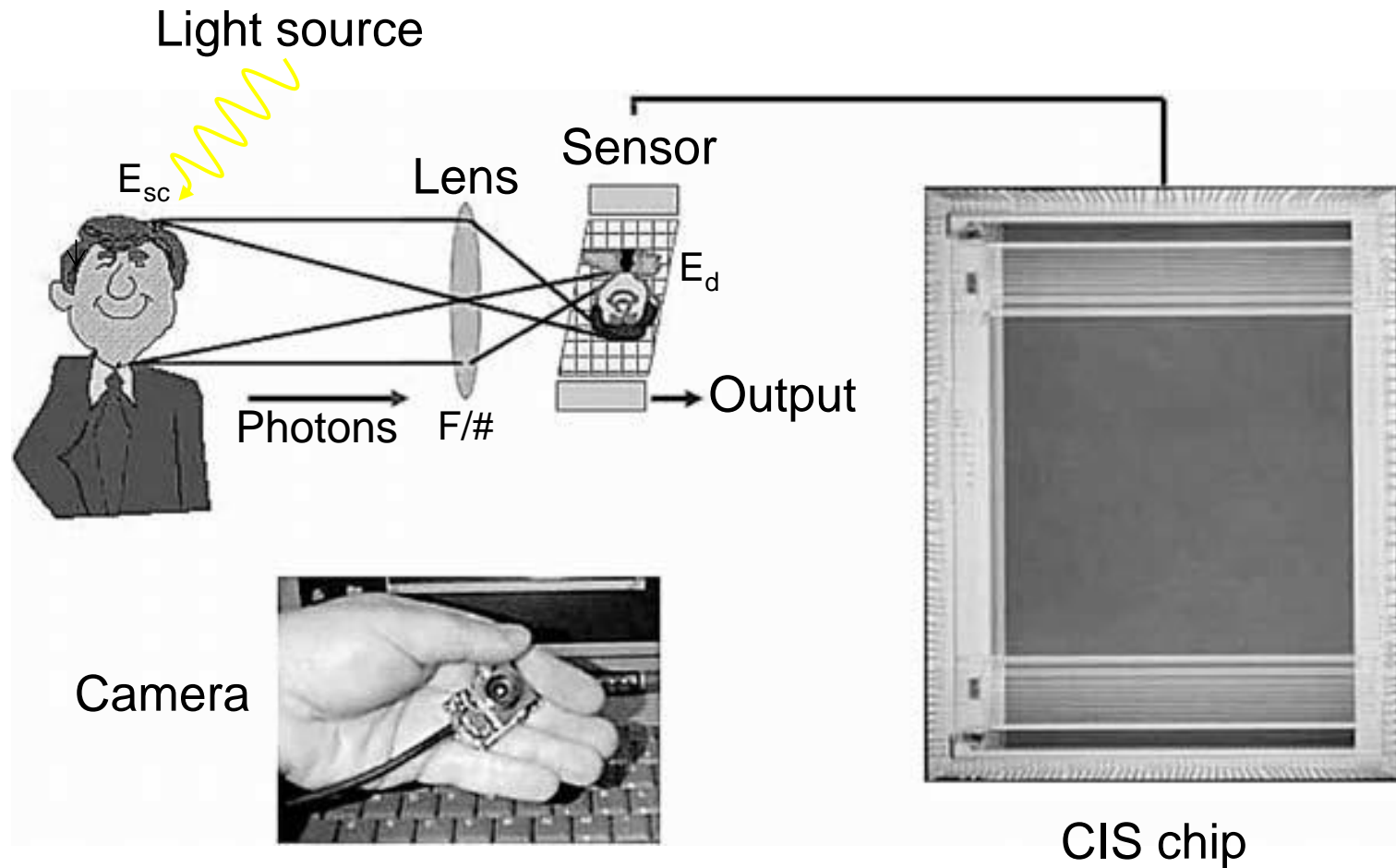
Agenda

- Key takaways from previous week
- Lecture2 – Photon detection and pixel circuits
 - References: Nakamura, Ch. 3

Recap from previous week

- Photon energy, $E_{\text{photon}} = h c / \lambda$ (J)
- RGB and YUV color representation
- Light level on sensor: $E_d = E_{sc} / 4F^2$ (lx or W/m²)
- Camera field of view: $FOV = 2\theta' = \tan^{-1}(y'/f)$

CMOS Image Sensor (CIS)



Ref: J Nakamura, ch-3

Optical format and effective array size

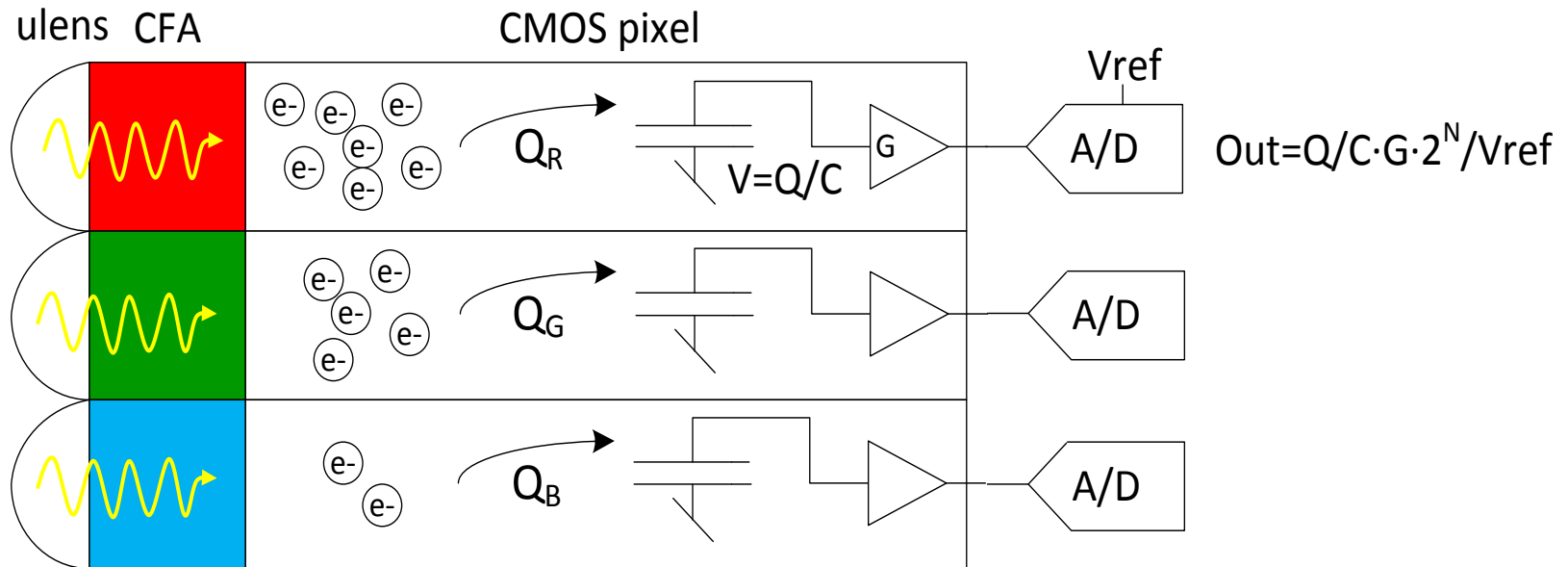
Format (type)	Diagonal (mm)	H (mm)	V (mm)
1	16.0	12.80	9.60
2/3	11.0	8.80	6.60
1/1.8	8.89	7.11	5.33
1/2	8.00	6.40	4.80
1/2.5	7.20	5.76	4.32
1/2.7	6.67	5.33	4.00
1/3	6.00	4.80	3.60
1/3.2	5.63	4.50	3.38
1/4	4.50	3.60	2.70
1/5	3.60	2.88	2.16
1/6	3.00	2.40	1.80

For DSLR

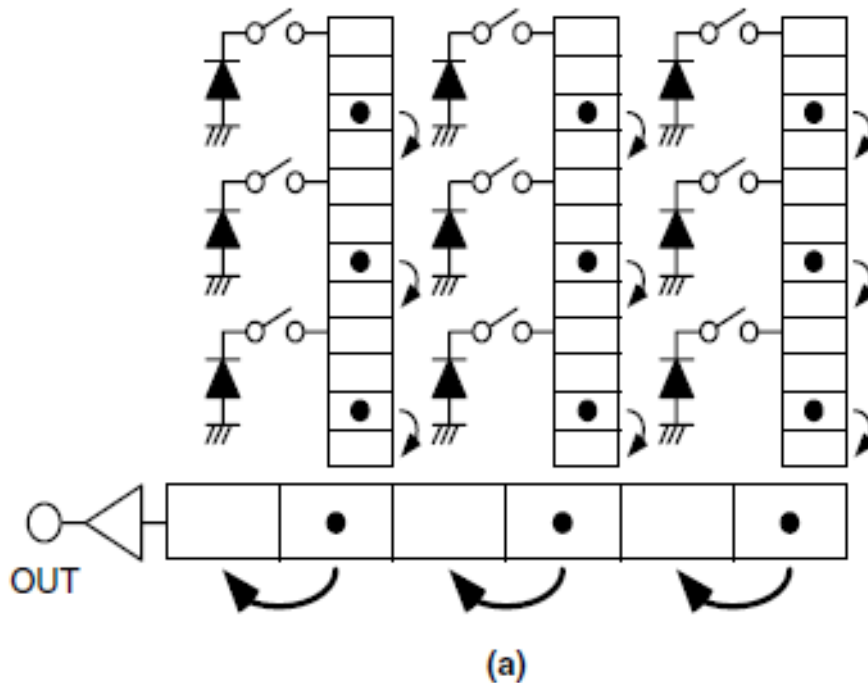
Format	Diagonal (mm)	H (mm)	V (mm)
35 mm	43.27	36.00	24.00
APS-DX	28.37	23.7	15.6
APS-C	27.26	22.7	15.1
APS-H	33.93	28.7	19.1
Four-thirds	21.63	17.3	13.0

Ref: Nakamura, ch-3

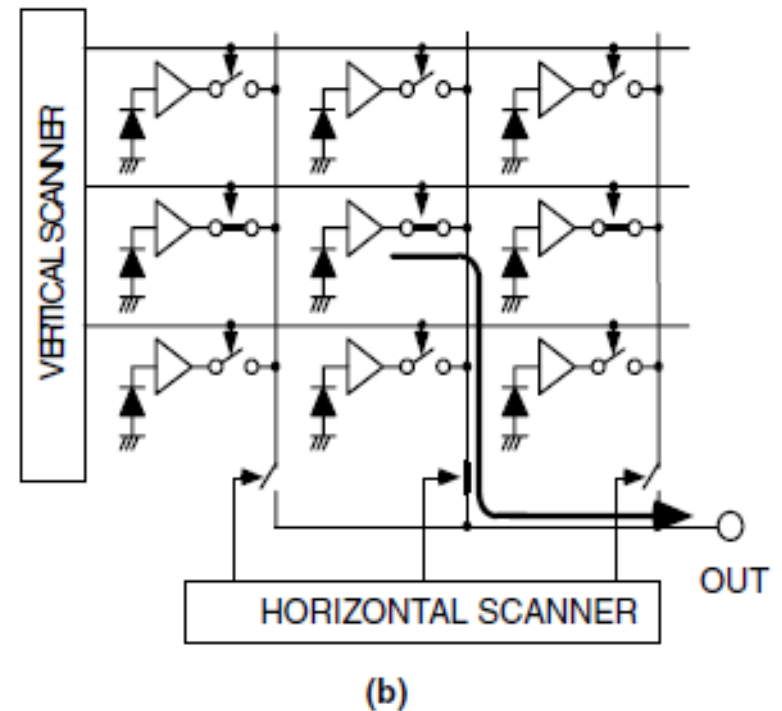
From photons to bits conceptually



CCD vs CMOS image sensors

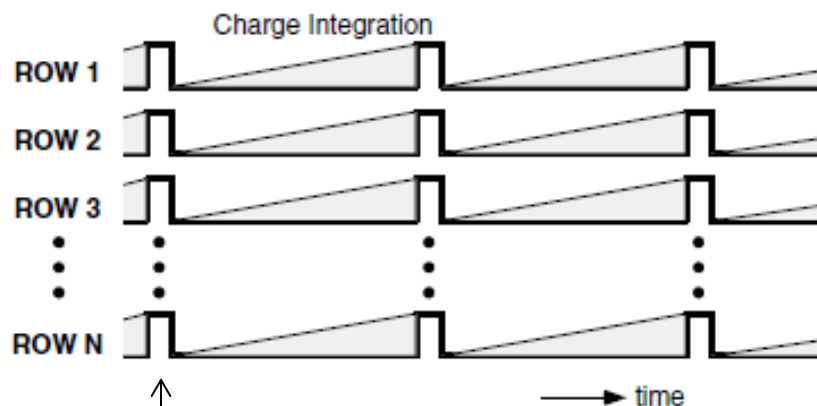


CCD



CMOS

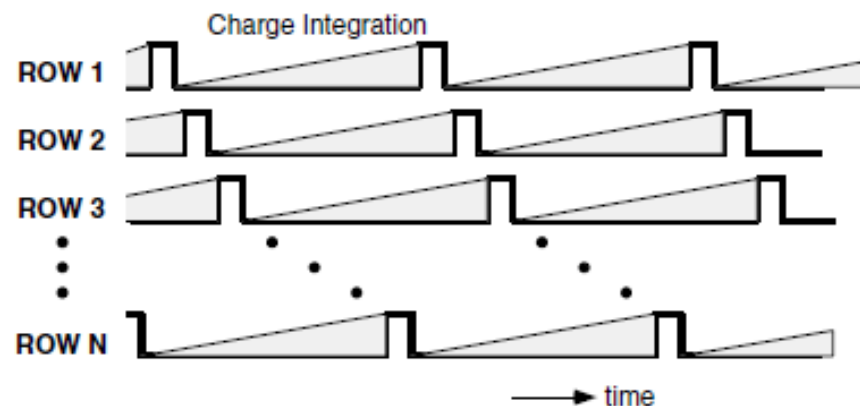
CCD vs CMOS capture timing



(a)

CCD

Global shutter, ie all pixel rows start and stop image capture simultaneously



(b)

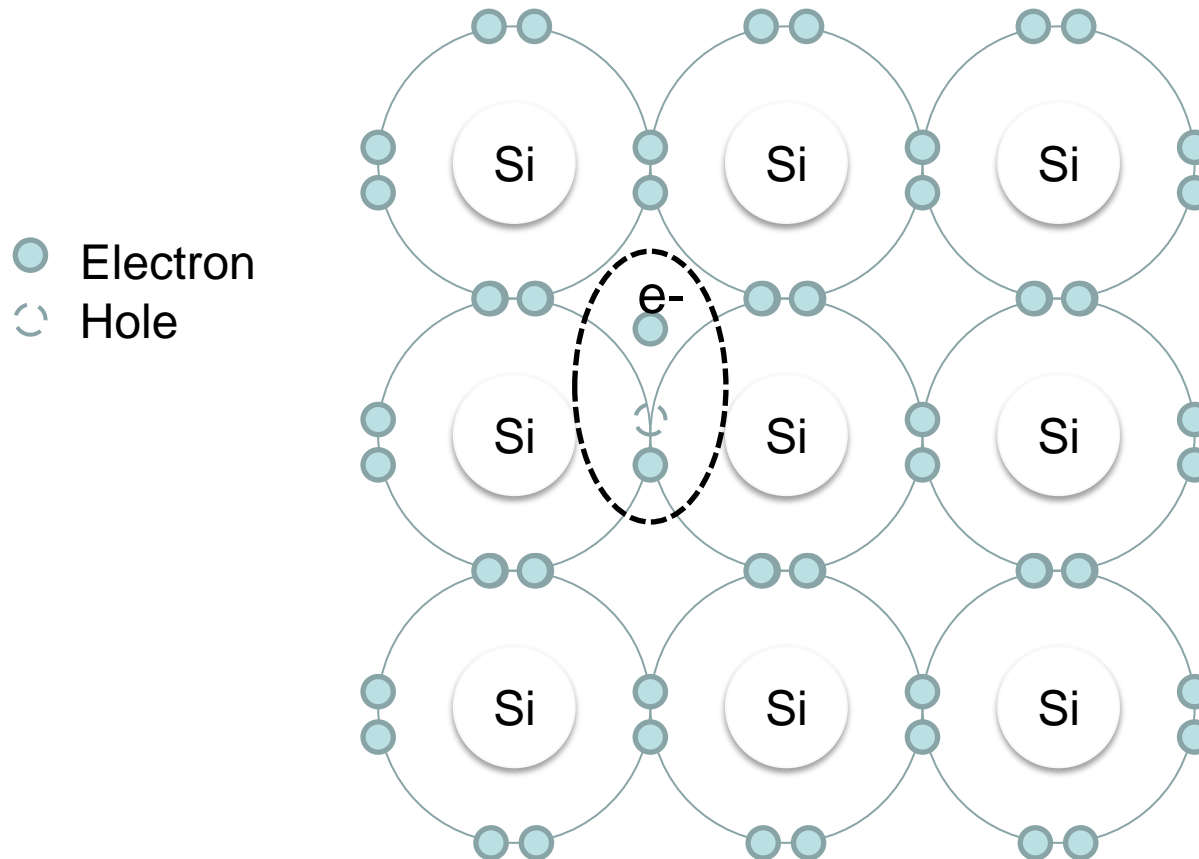
CMOS

Rolling shutter, ie fixed time delay between each row

INF5442

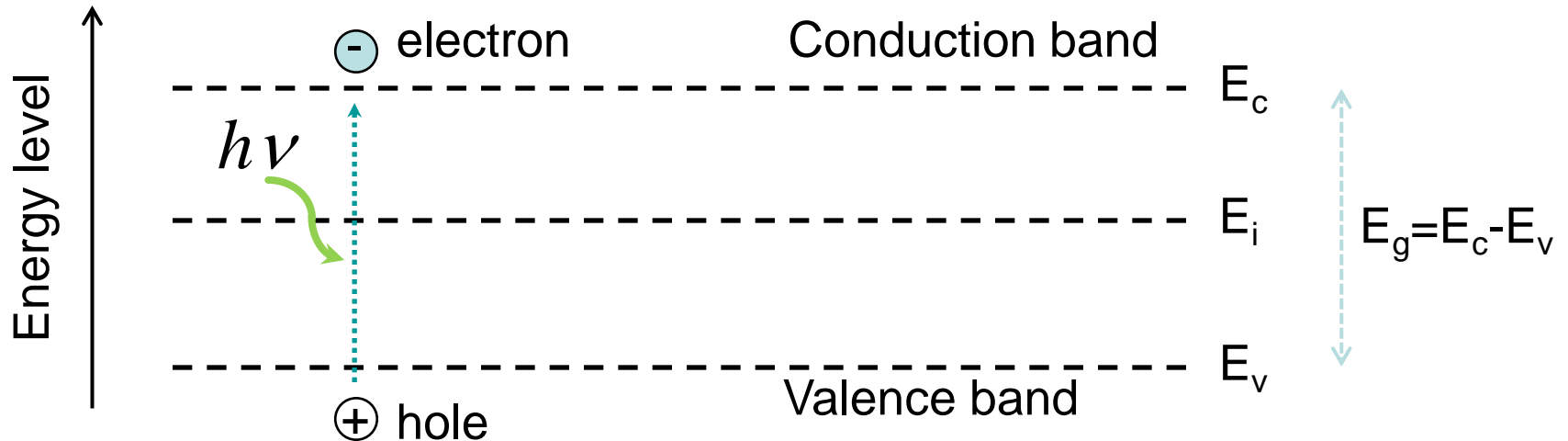
PHOTON DETECTION IN SILICON

Photon absorption in Silicon generates electron-hole pairs



Pixels measure light intensity by absorbing photons. Each detected photon generates an electron-hole pair.

Detection of photons i Silicon (Photoelectric effect)



Photon energy (Joule) : $E = h\nu = h \frac{c}{\lambda}$

Condition for detection : $h\nu \geq E_g \Rightarrow \lambda \leq \frac{hc}{E_g}$

Band-gap in Silicon: $E_g \approx 1,8 \cdot 10^{-19} J$

Cut-off wavelength in Silicon :

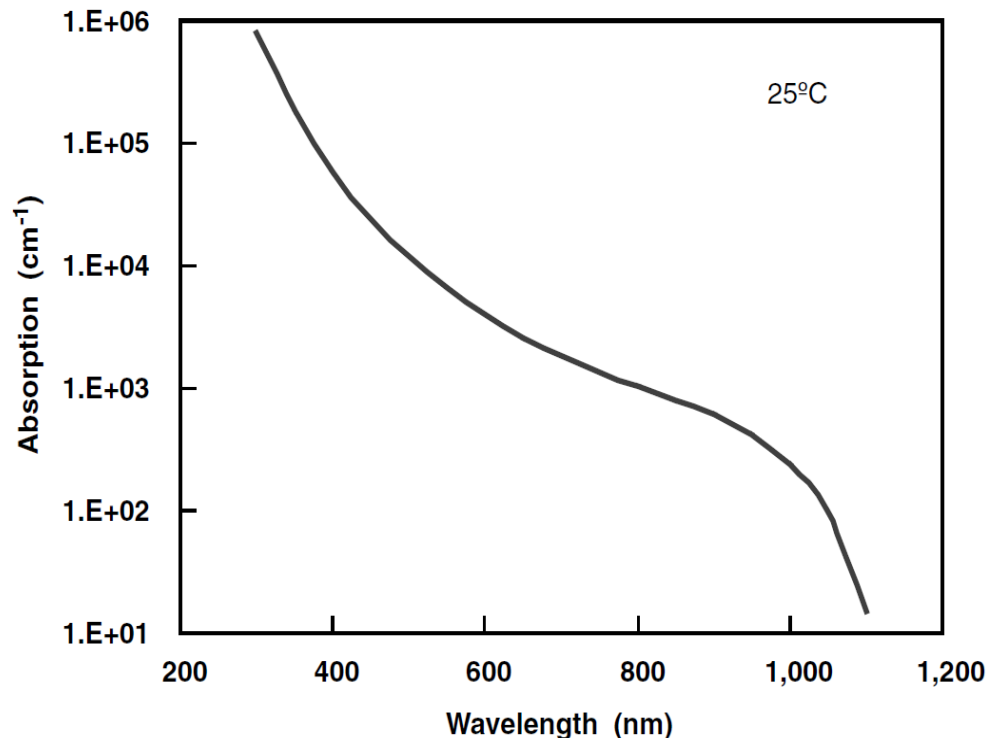
$\lambda_{\text{cut-off}} \approx 1,1 \mu\text{m}$

Absorption of light in Silicon

$\Phi(x)$: photon flux, α : absorption coefficient (cm^{-1})

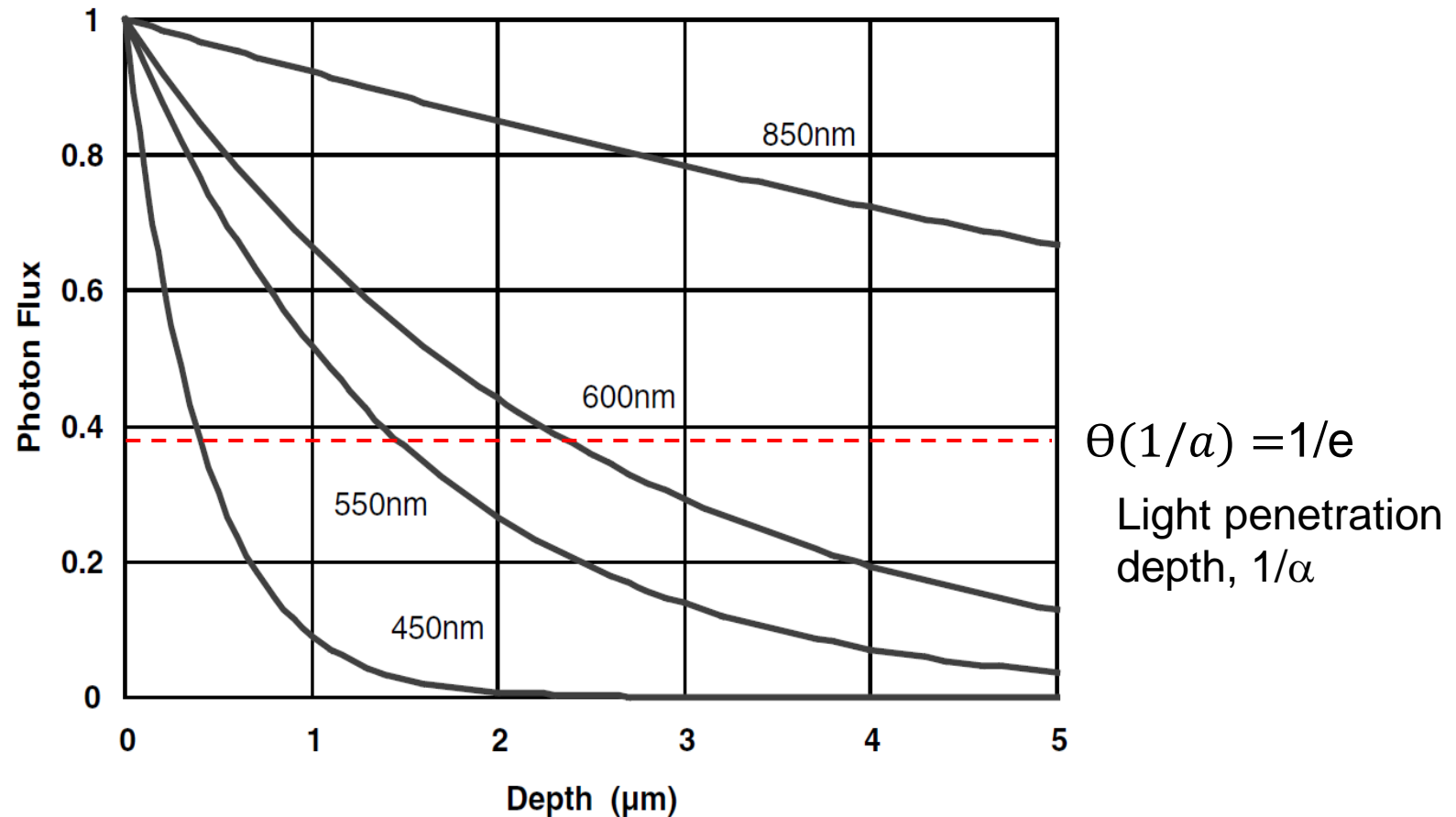
x : distance from silicon surface (cm)

$$\Phi(x) = \Phi_0 \exp(-\alpha x)$$



Ref: J Nakamura, ch-3

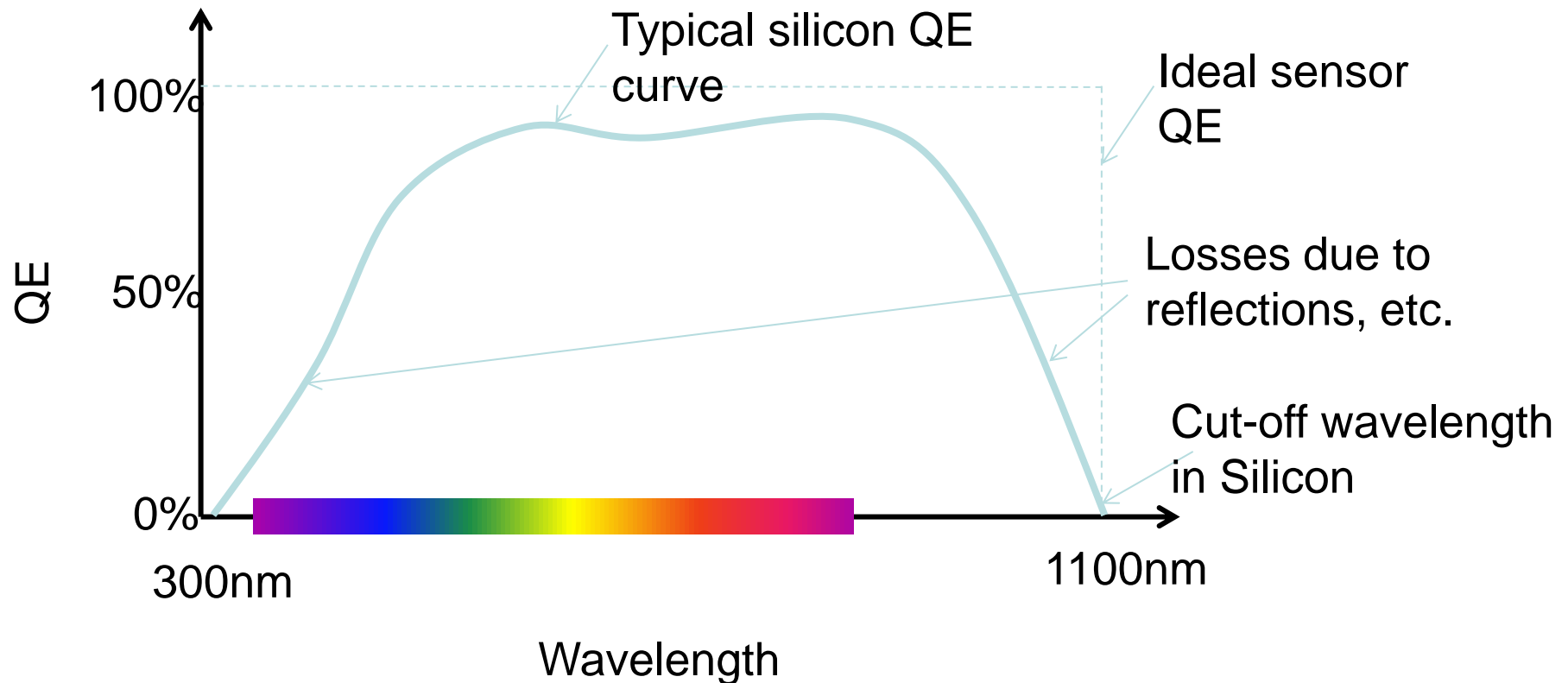
Absorption of light in Silicon (intensity versus depth)



Ref: J Nakamura, ch-3

Quantum efficiency (QE)

QE = likelihood of detecting a photon



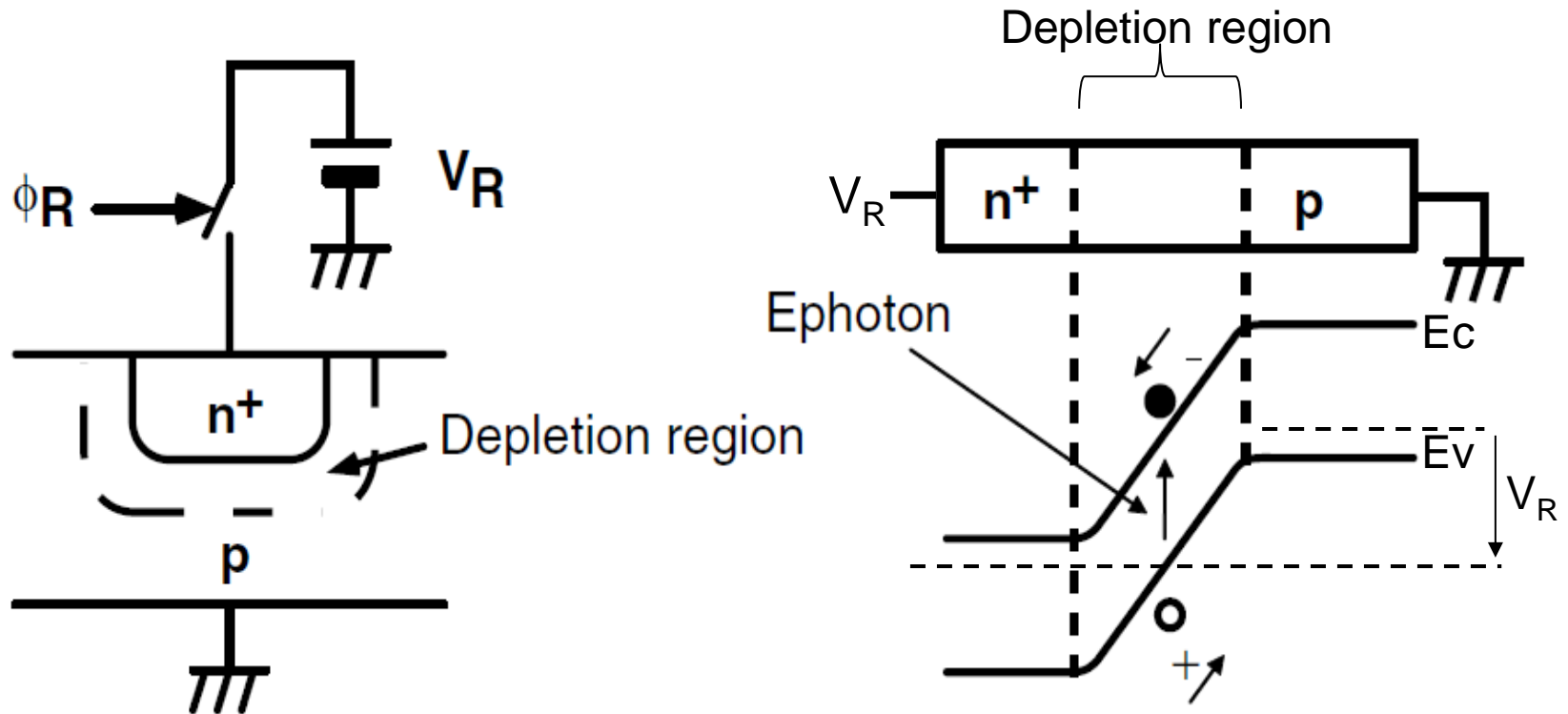
More references

- Books
 - [Physics of Semiconductor Devices](#) by Simon M. Sze and Kwok K. Ng (Oct 27, 2006)
 - [Solid-State Imaging with Charge-Coupled Devices \(Solid-State Science and Technology Library\)](#) by [Albert J. P. Theuwissen](#) (Mar 31, 1995)
- Internet
 - Wikipedia
 - <http://pveducation.org/pvcdrom/pn-junction/conduction-in-semiconductors>

INF5442

PHOTODIODE STRUCTURE AND PIXEL CIRCUITS

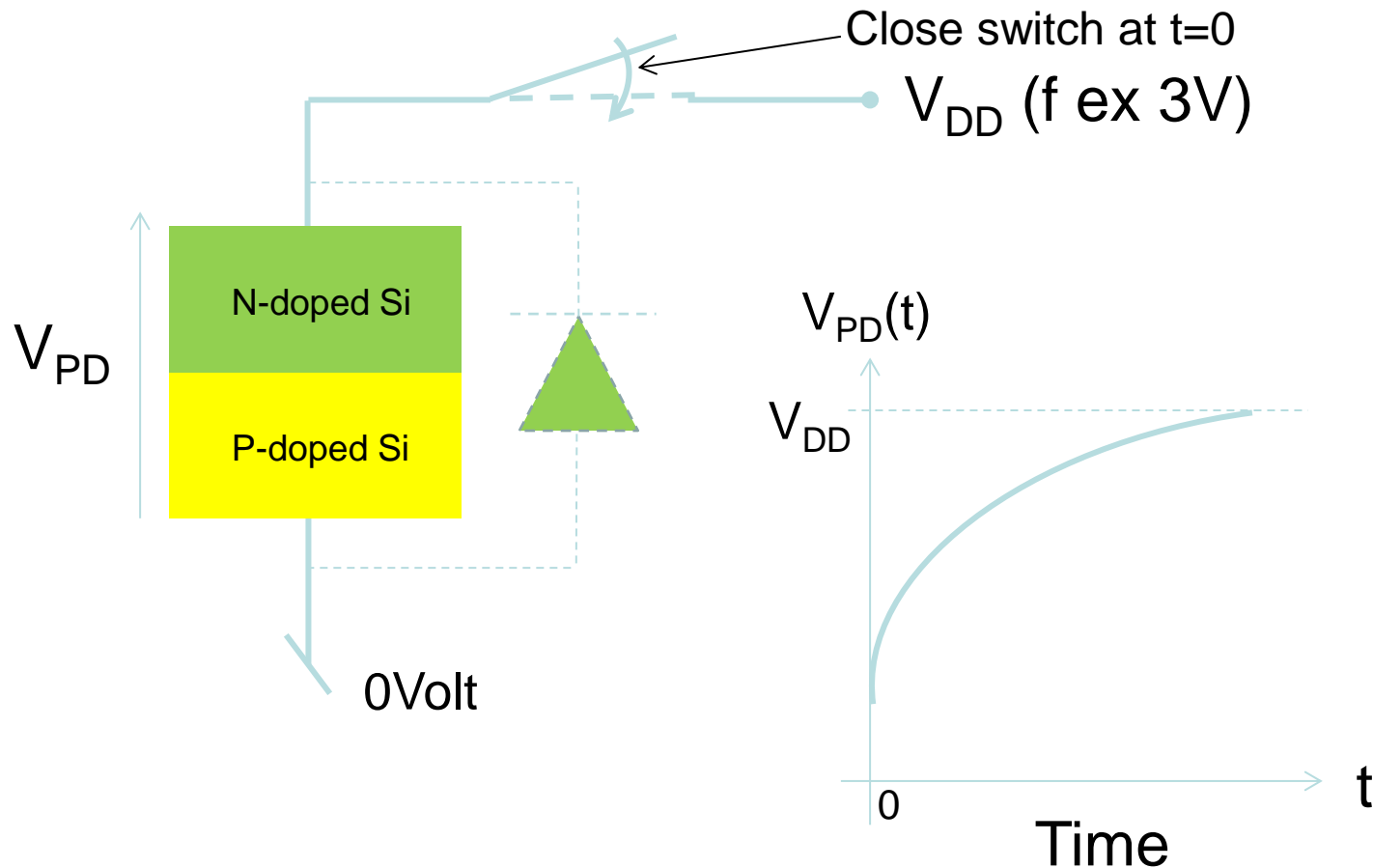
Light detection in reverse biased photodiode



Ref: Nakamura et al

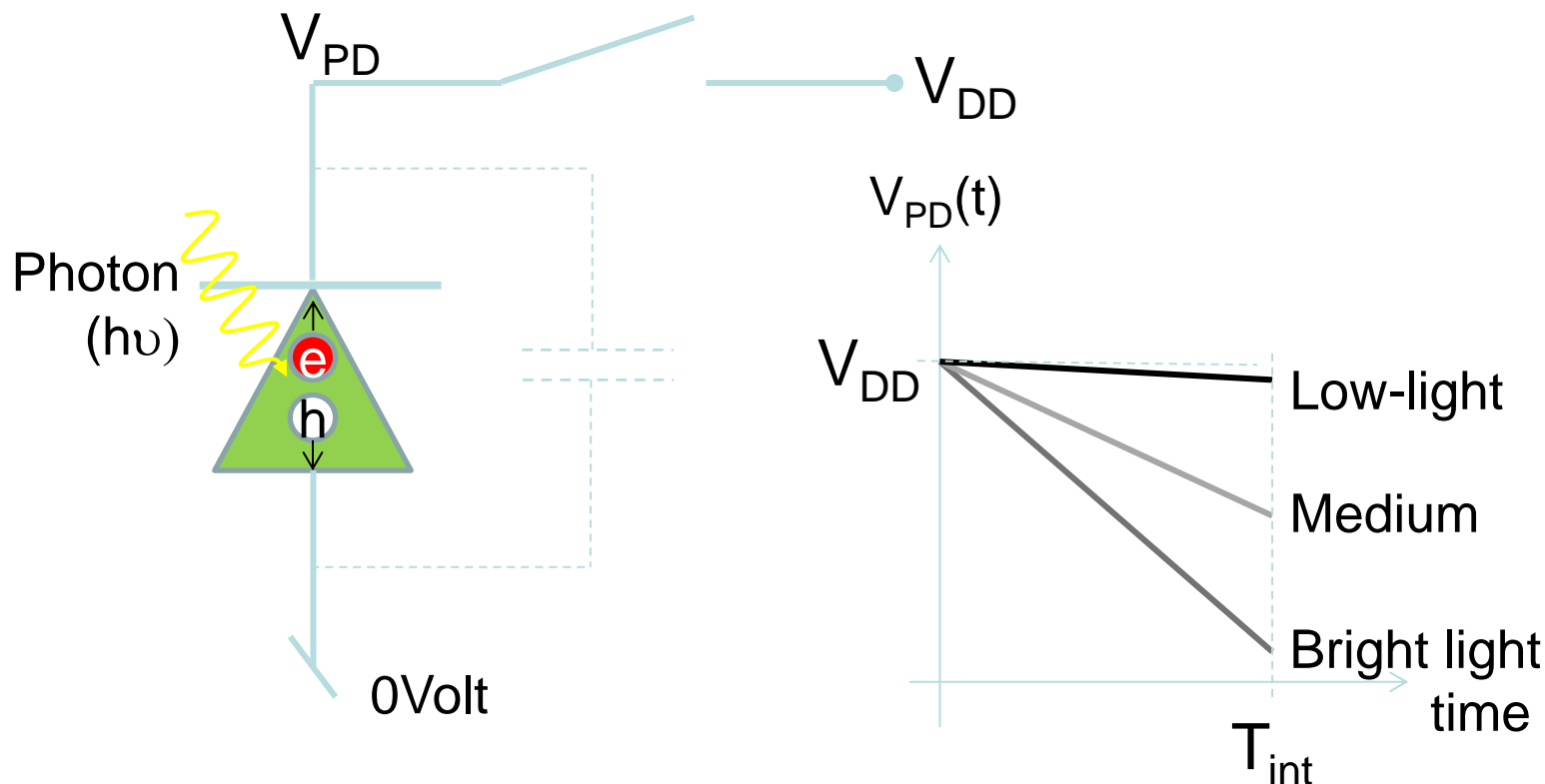
Photodiode detection principle (1/3)

Step-1: Reset diode (remove old signal) by connecting it to power supply (VDD)



Photodiode detection principle (2/3)

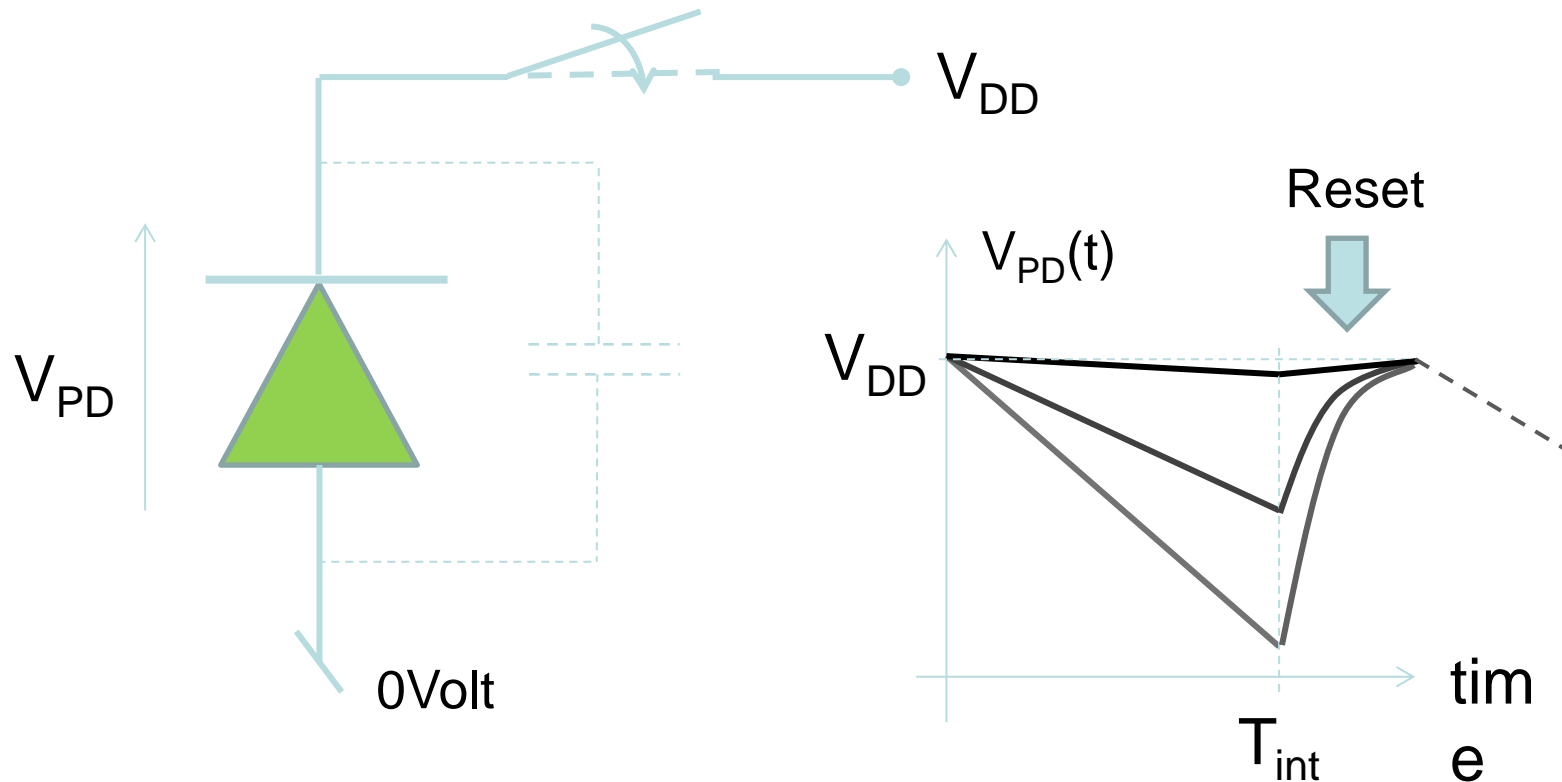
Step-2: Accumulate signal during exposure time (T_{int} f ex 10ms)



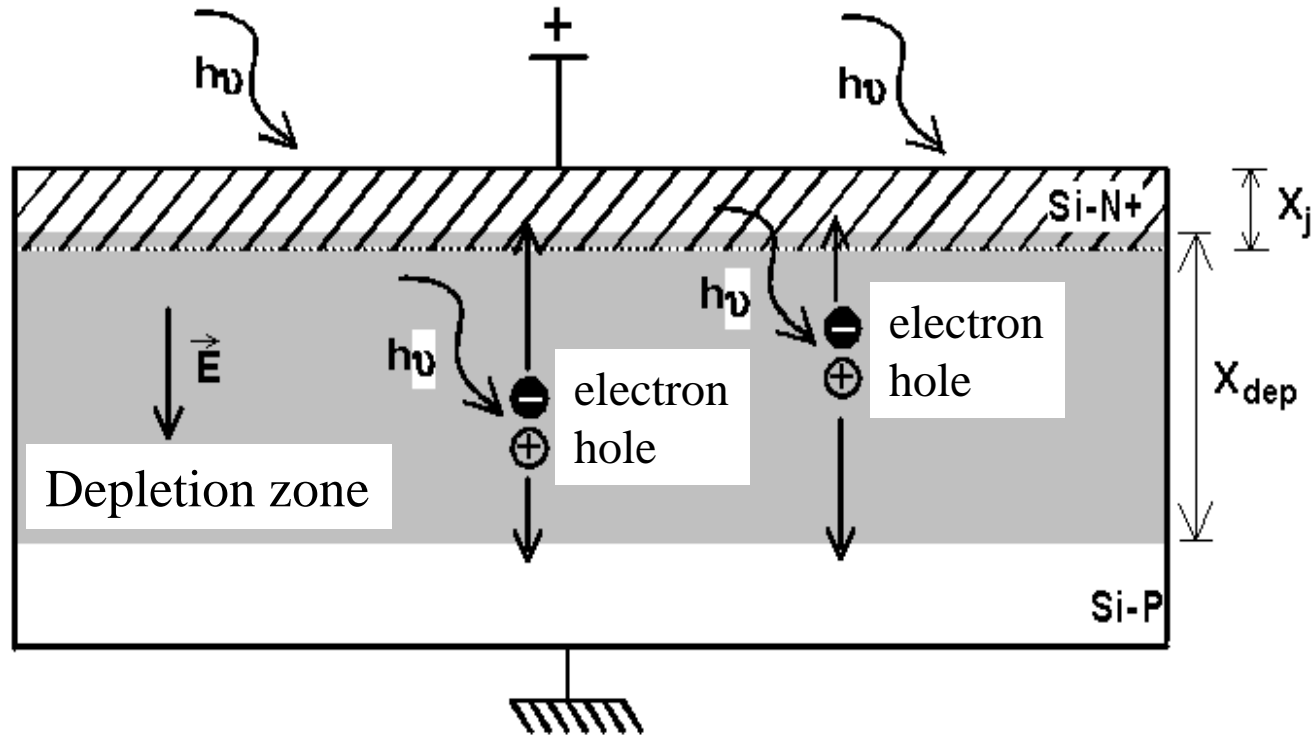
$$\Delta V_{PD} = V_{DD} - V_{PD}(T_{\text{int}})$$

Photodiode detection principle (3/3)

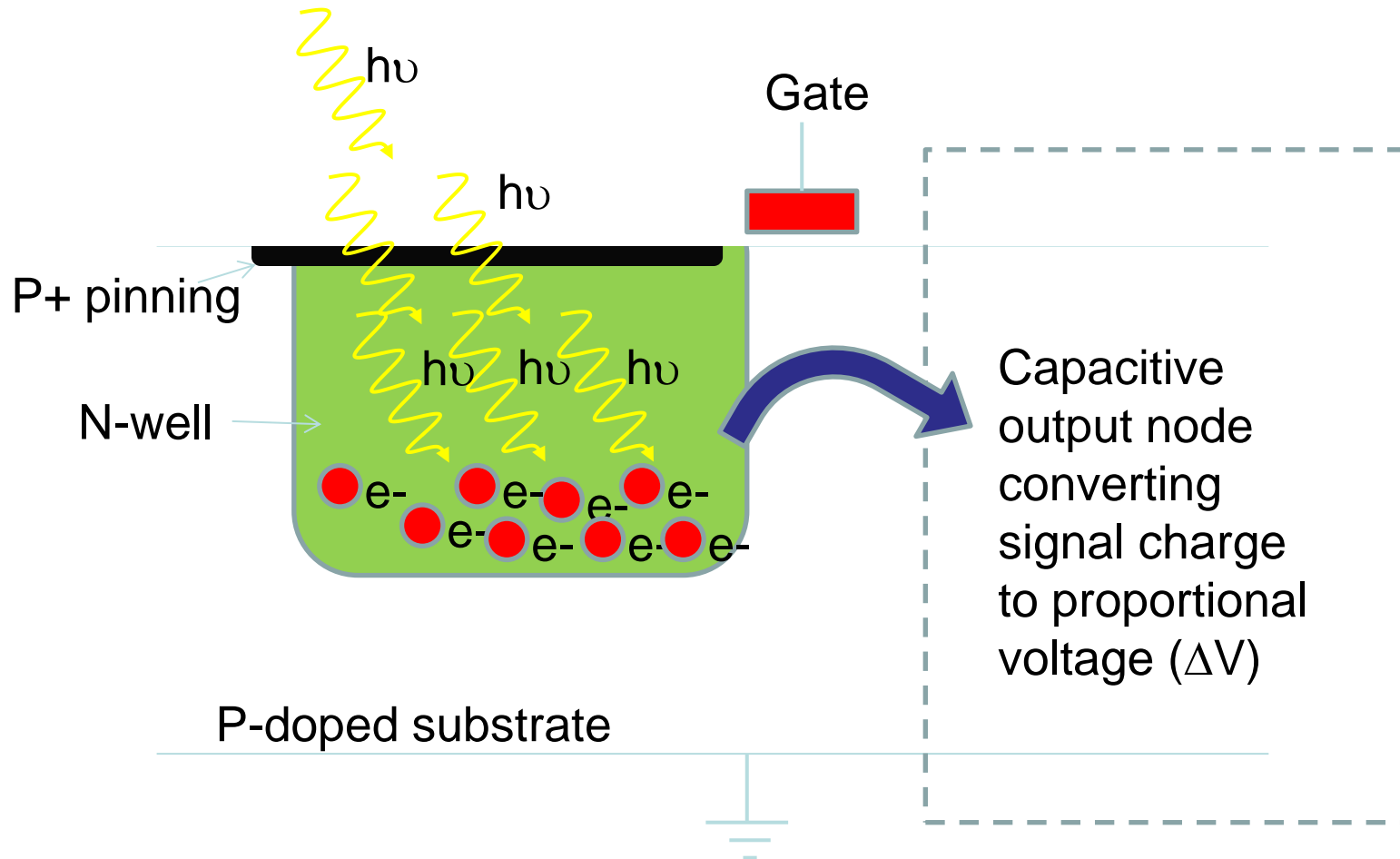
Step-3: Sample output, then reset and start new exposure



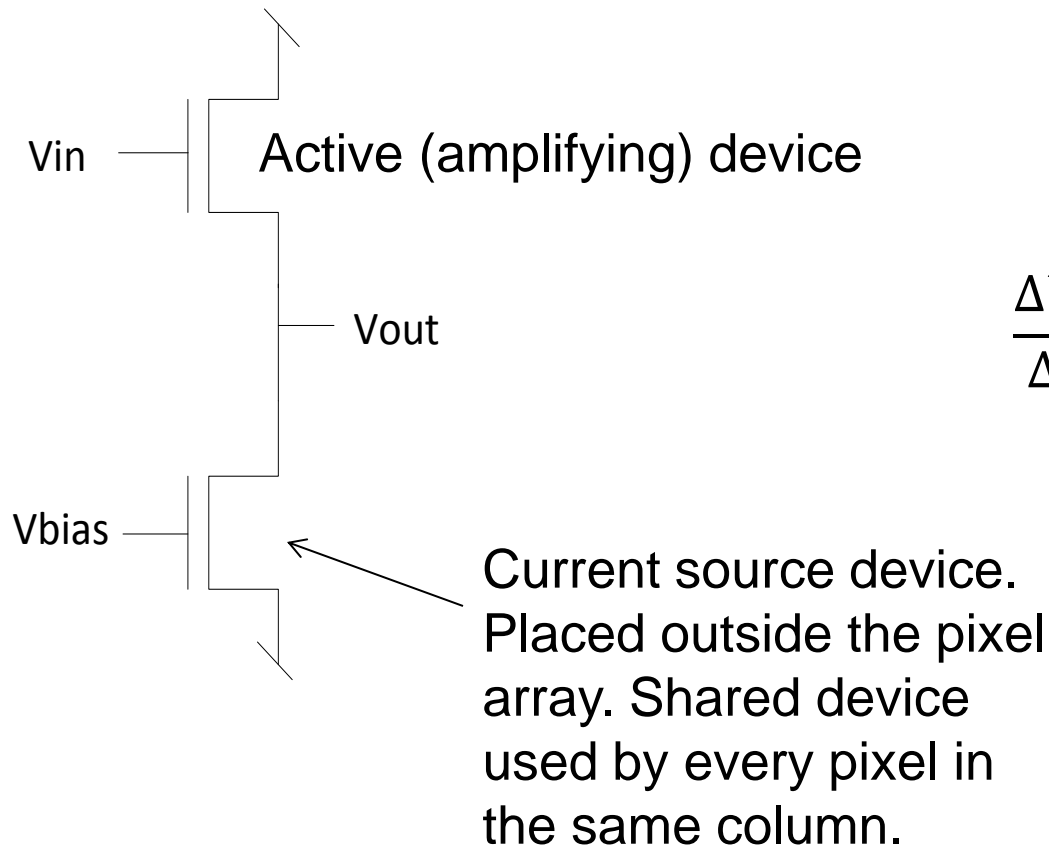
Photodiode detection principle



Pinned photodiode structure



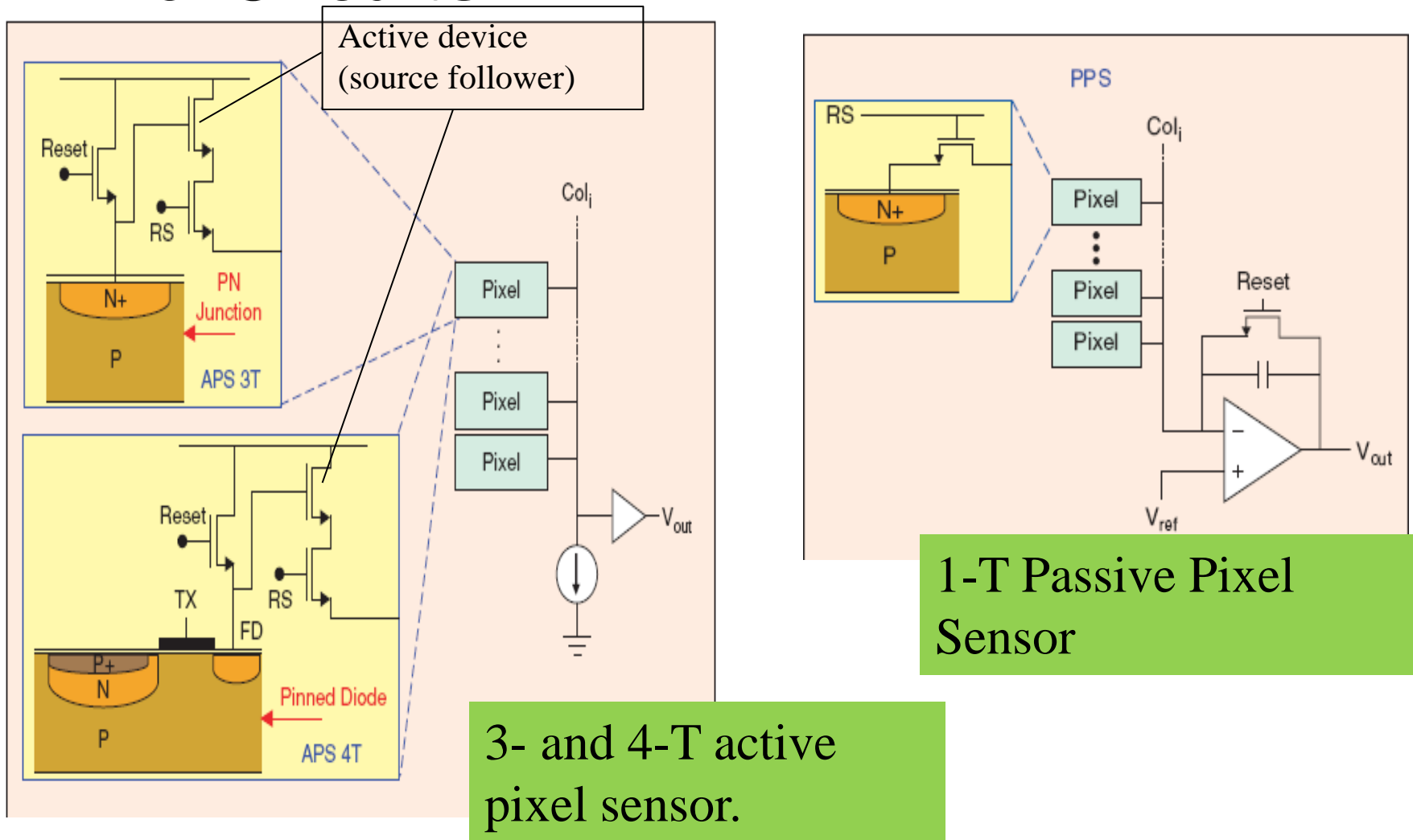
NMOS source follower circuit used in CMOS active pixel sensors



Gain equation:

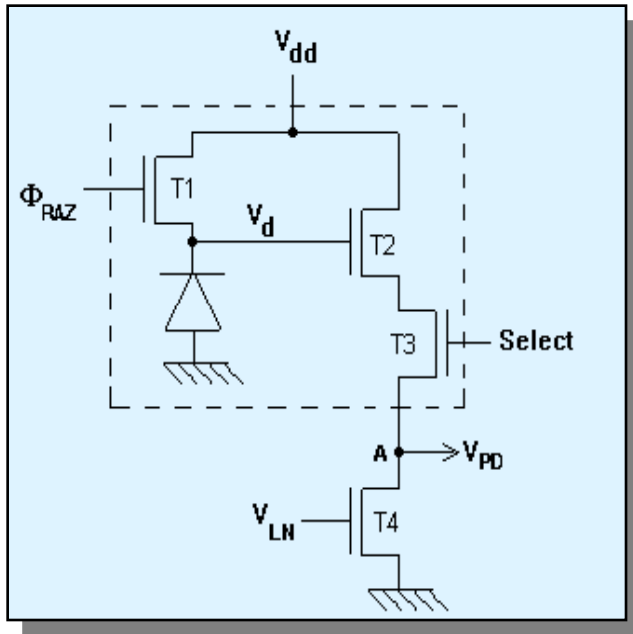
$$\frac{\Delta V_{out}}{\Delta V_{in}} = \frac{g_m/g_d}{1 + g_m/g_d} \approx 0.8$$

Pixel Circuits

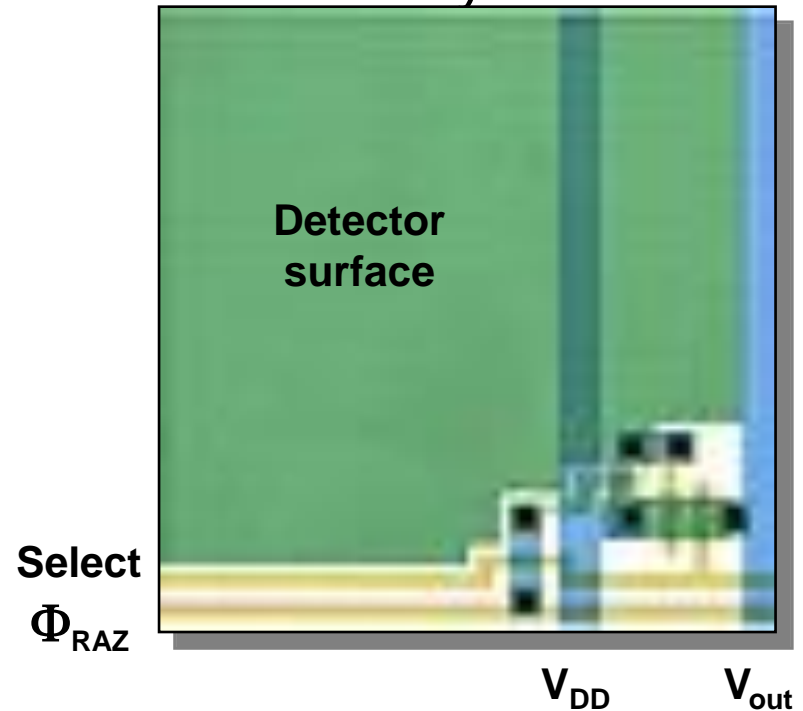


3T Active Pixel Structure

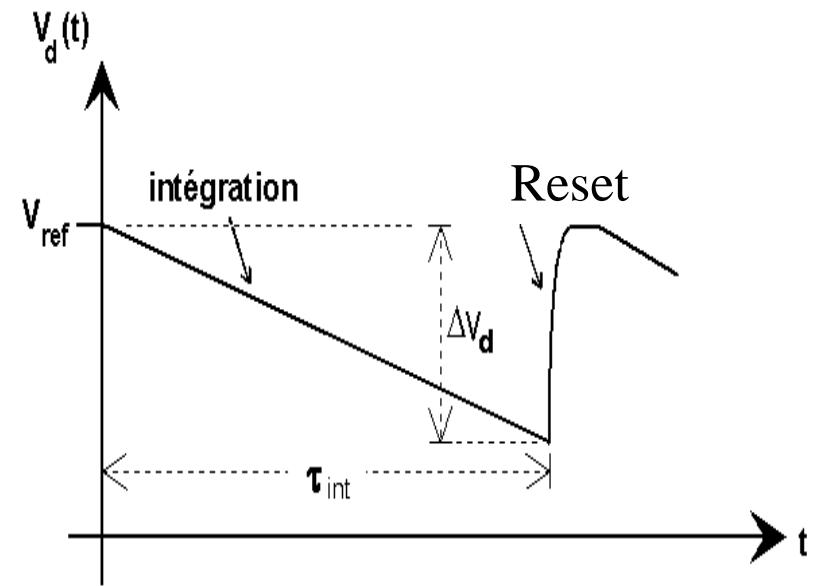
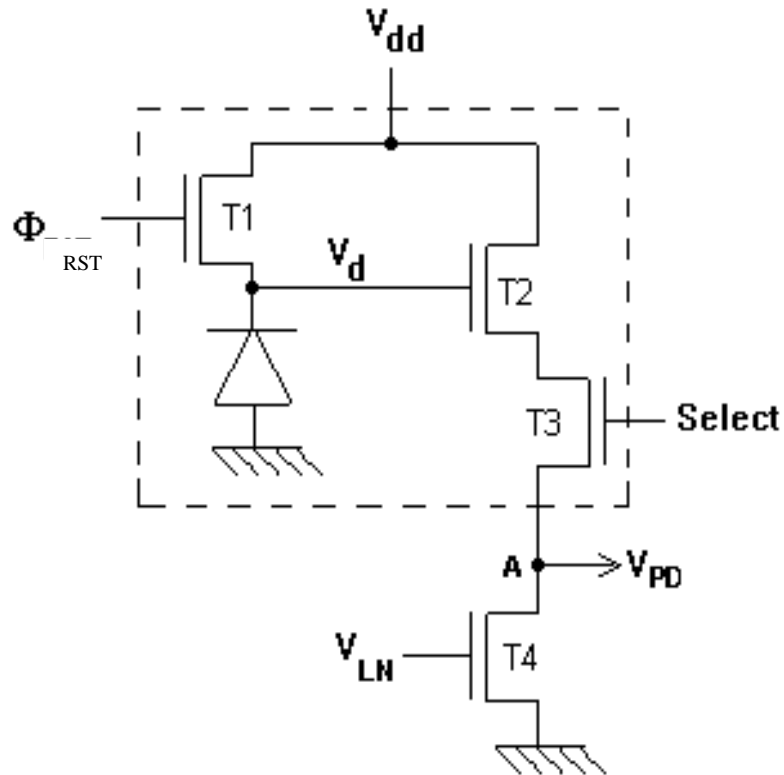
Schematics



Layout

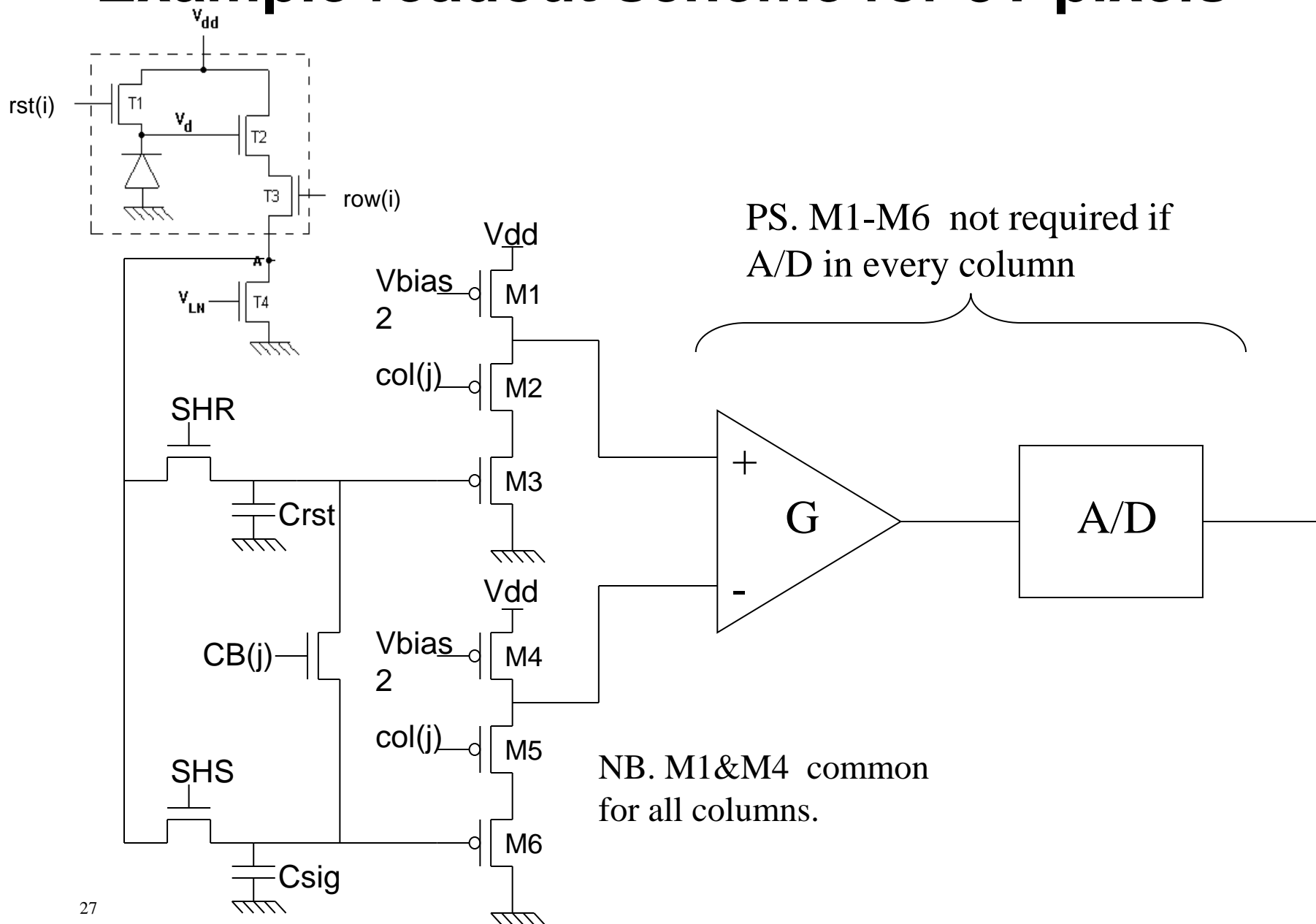


3T active pixel

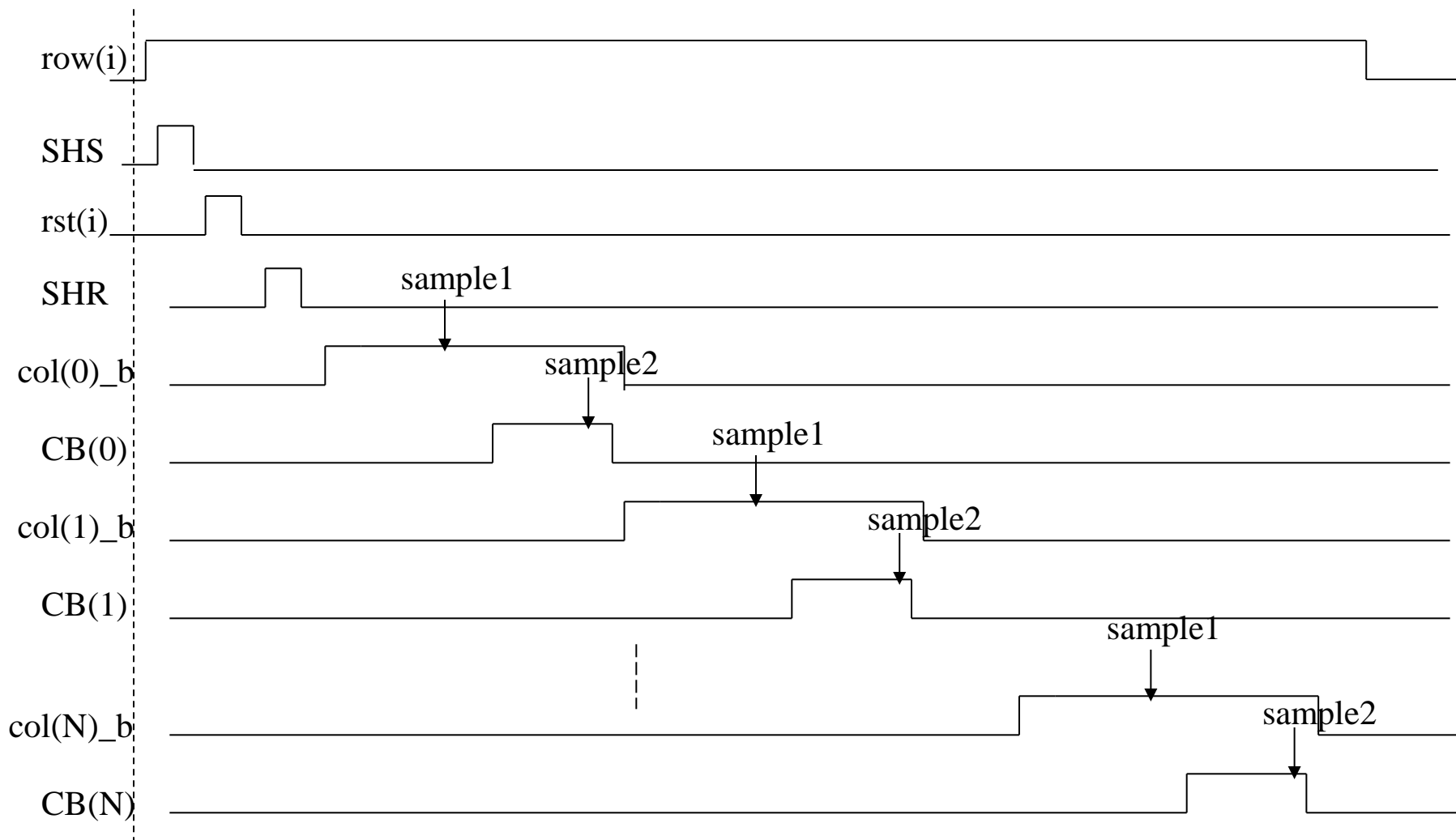


$$V_d(t) = V_{ref} - \frac{1}{C_d} \cdot \int_0^t I_{phot}(u) \cdot du$$

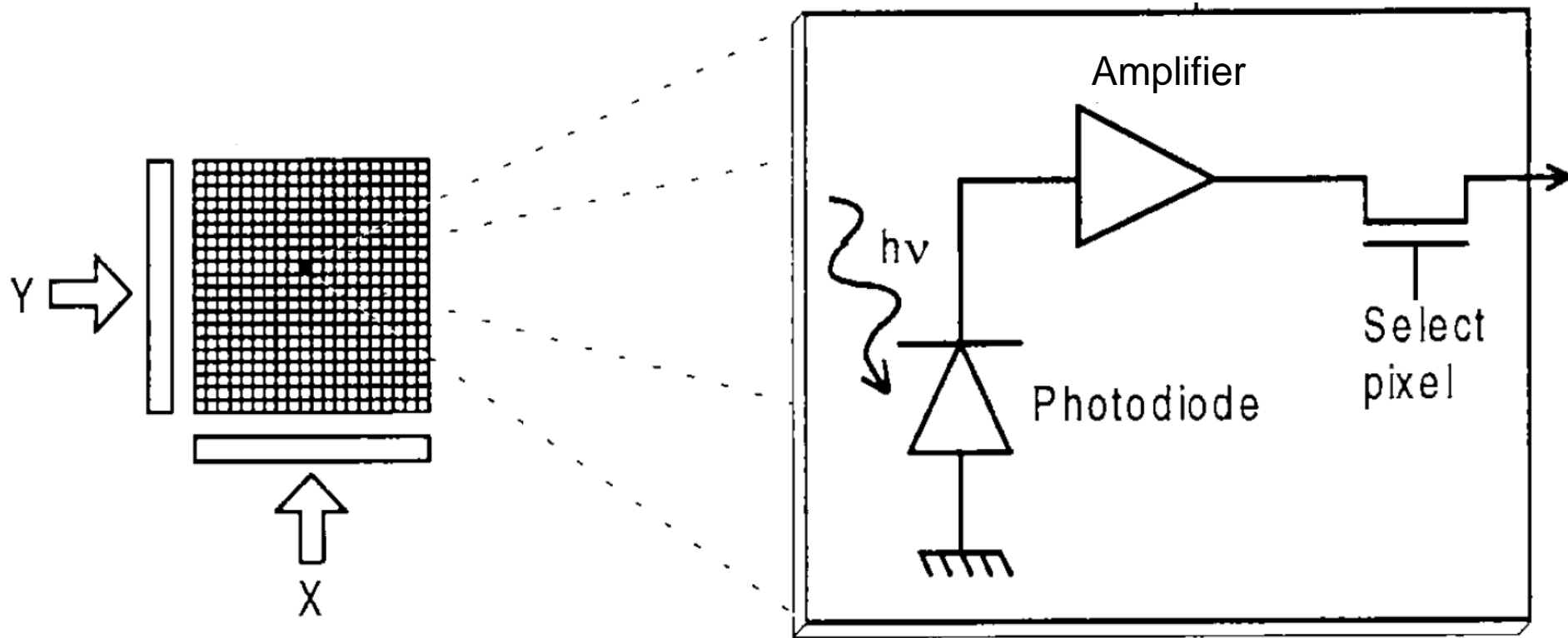
Example readout scheme for 3T pixels



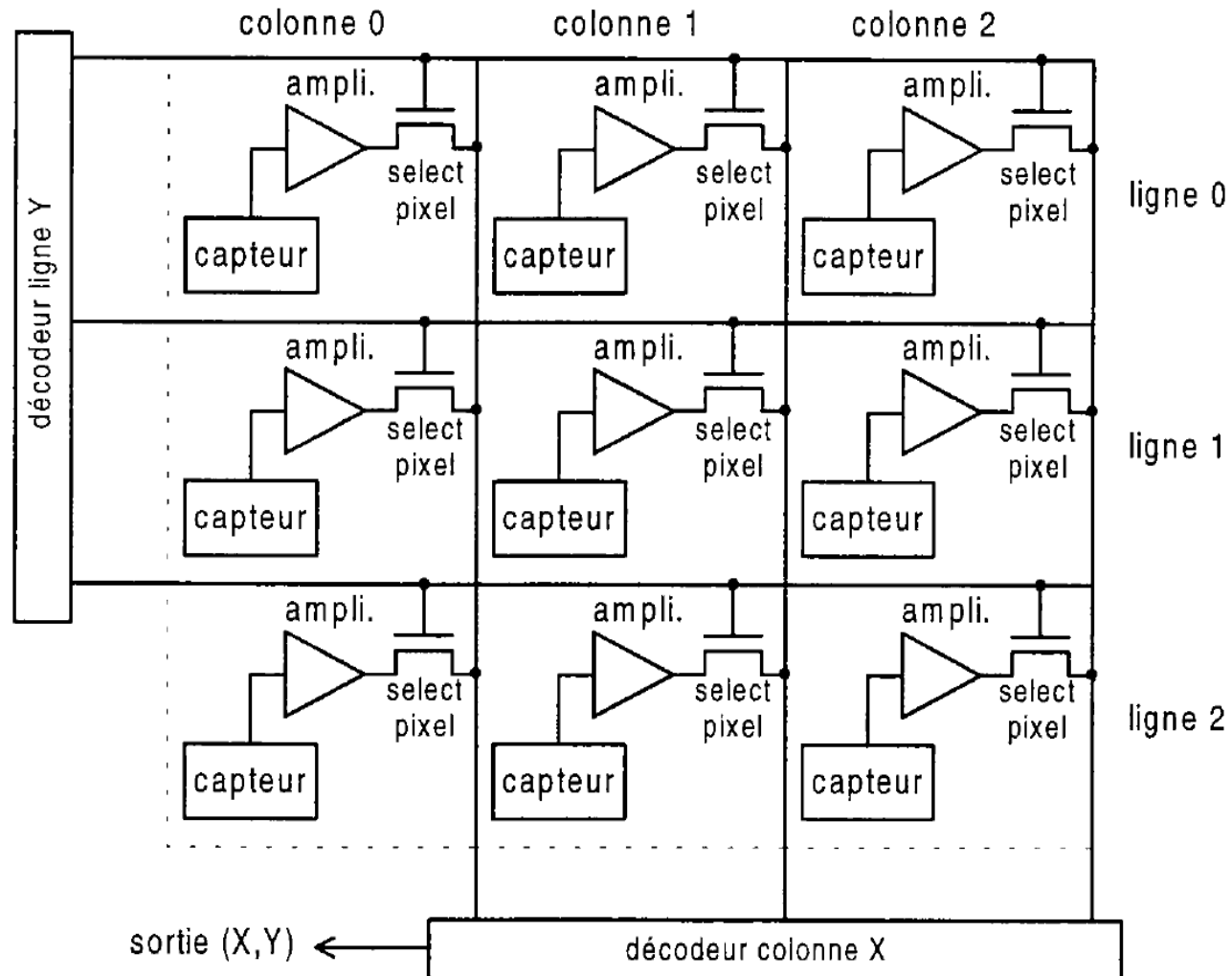
Timing diagram for 3T row readout



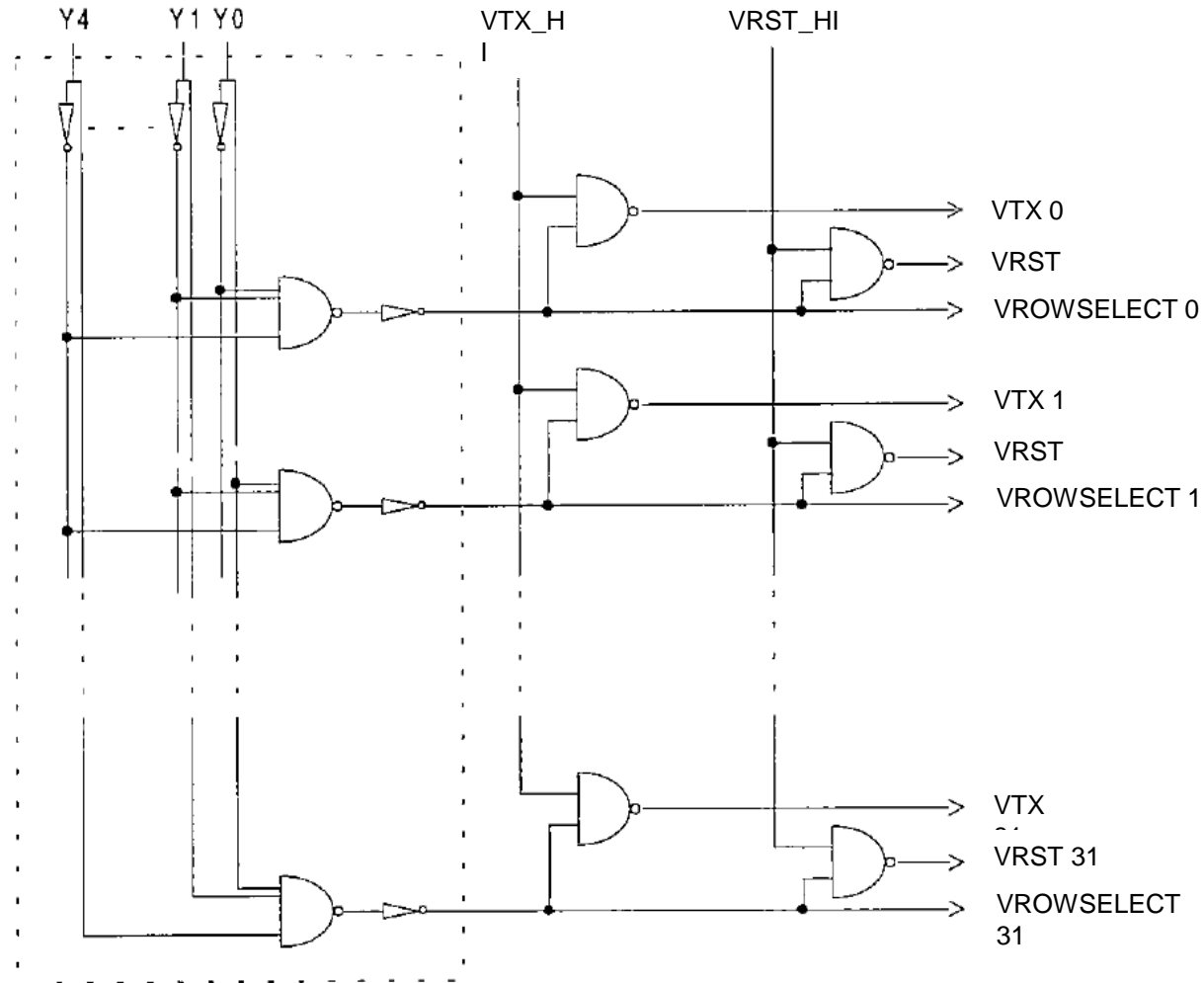
CMOS Active Pixel Sensor



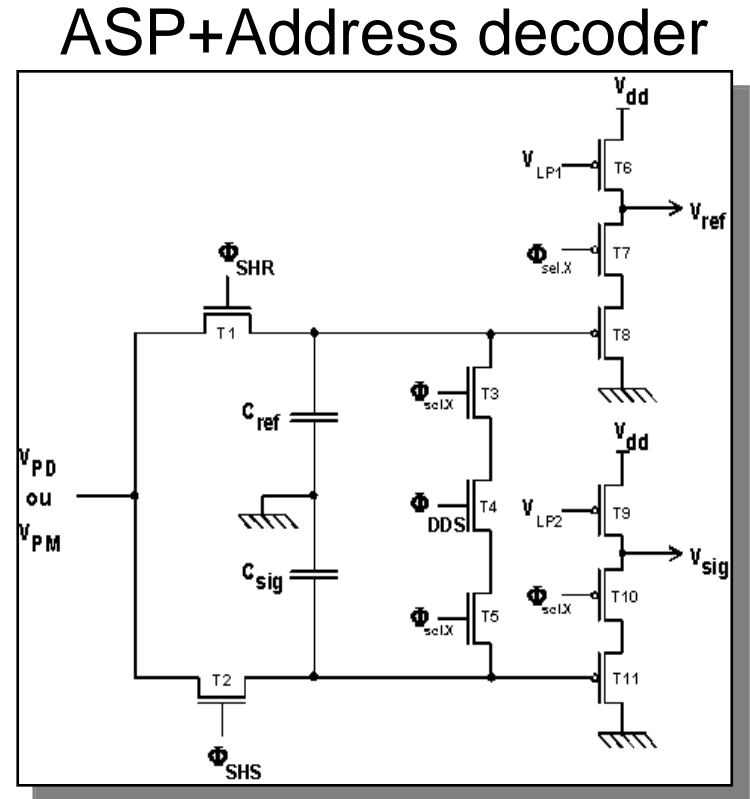
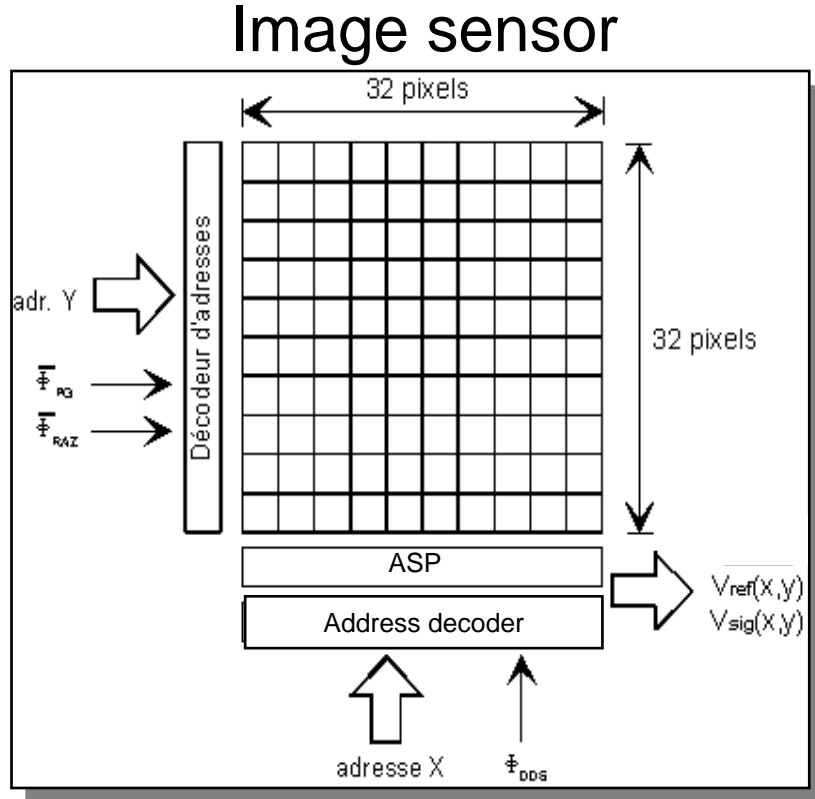
CMOS Active Pixel Sensor



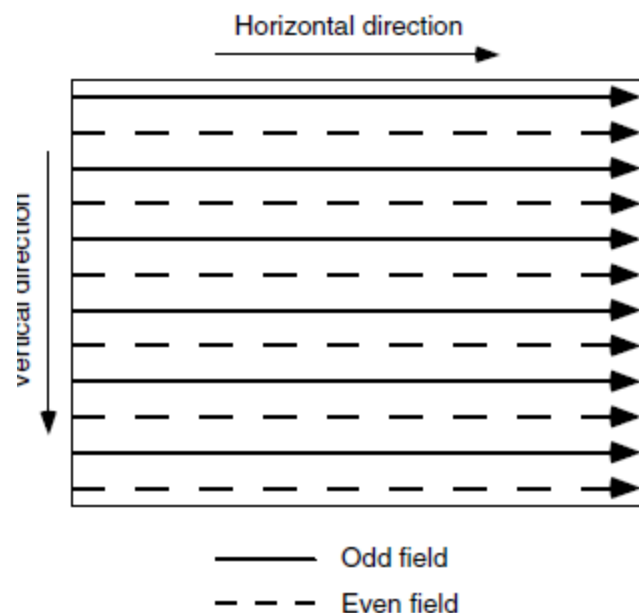
Row decoder circuit



APS Detector Organization

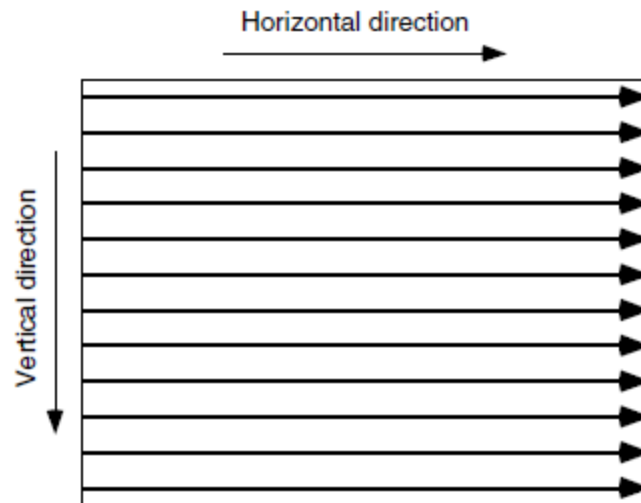


Interlaced scan versus progressive scan



(a)

Interlaced scan
(output even and odd fields
sequentially, ie trade off
vertical resolution against
bandwidth and power)

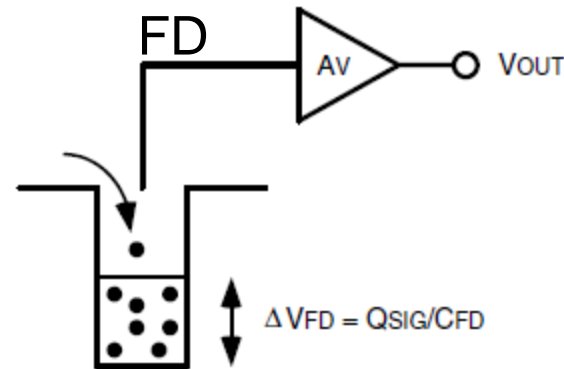


(b)

Progressive scan
(output every pixel row in
every frame for maximum
resolution)

Conversion gain

Charge detection scheme:



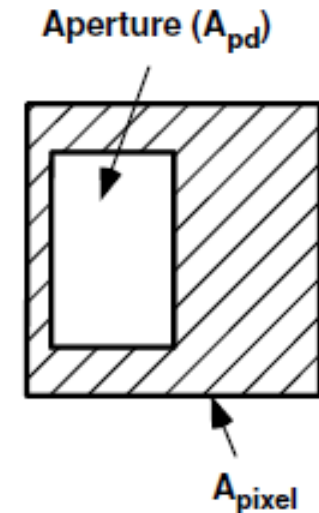
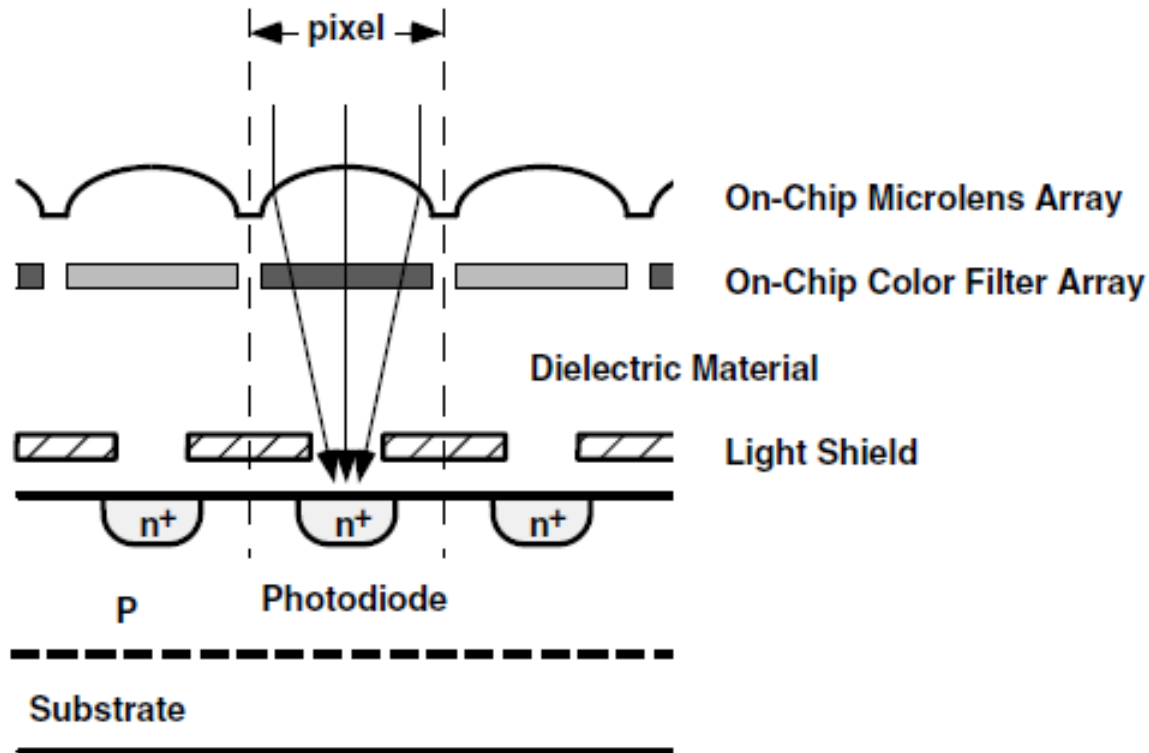
Conversion gain: $C.G. = \frac{q}{C_{FD}} \text{ } [\mu\text{V/electron}]$

$$q = 1.6 \times 10^{-19} \text{ C}$$

C_{FD} = floating diffusion capacitance

$$\text{Voltage swing at FD node: } \Delta V_{FD} = CG \ S_{\text{electrons}}$$

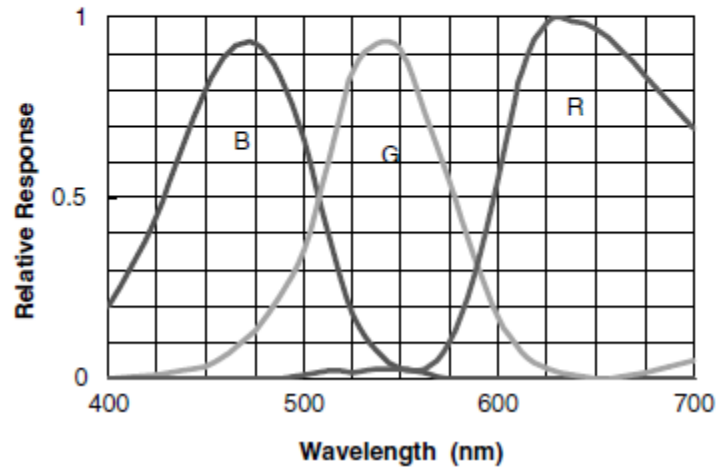
Photodiode in a pixel



$$\text{Fill factor} = (A_{pd} / A_{pix}) \times 100 \quad [\%]$$

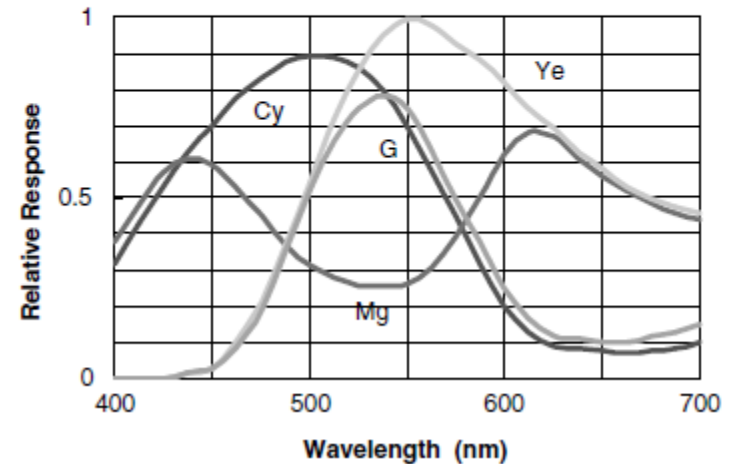
Bayer CFA versus CMY CFA

G	R	G	R
B	G	B	G
G	R	G	R
B	G	B	G



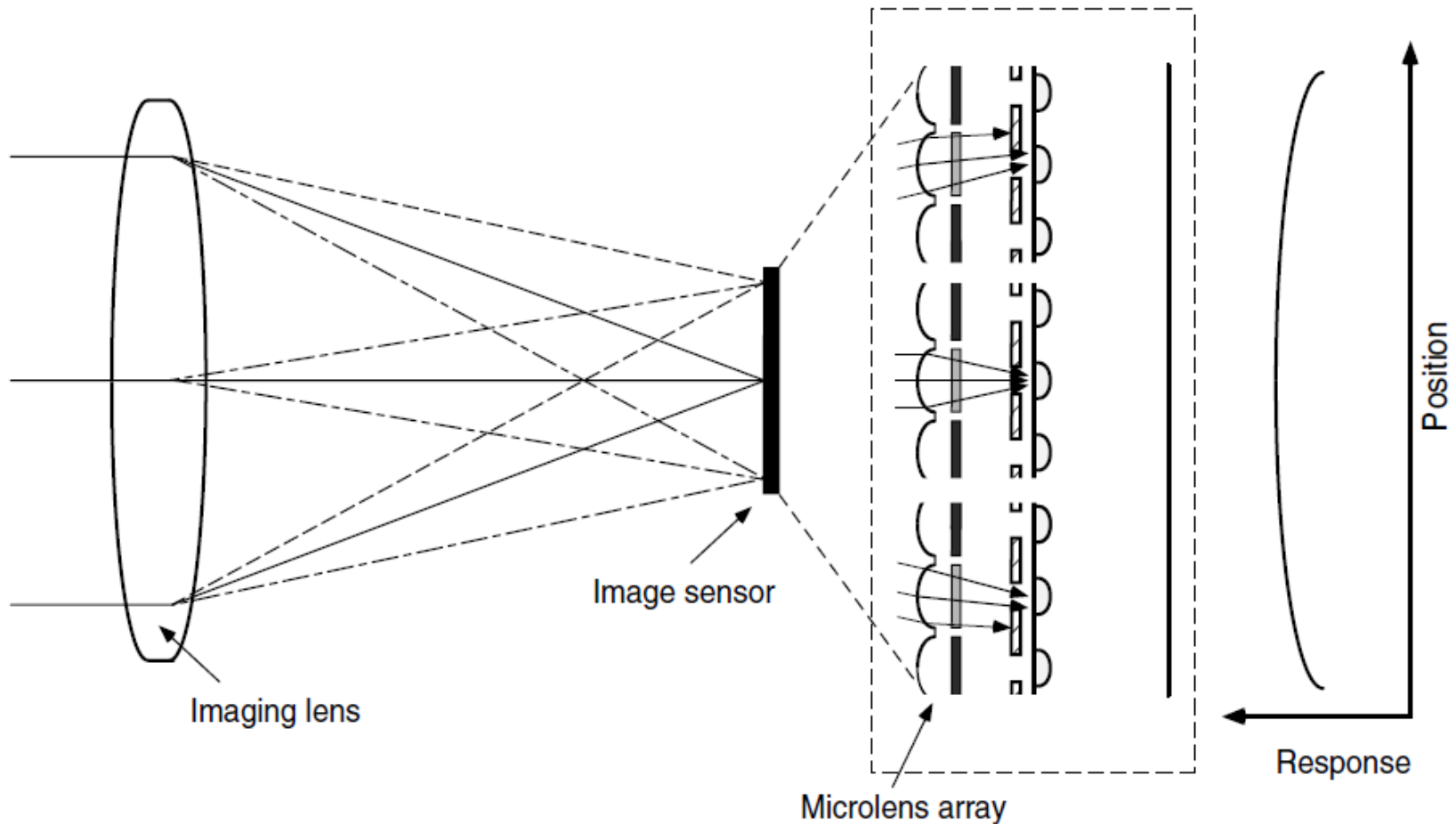
Bayer CFA

Mg	G	Mg	G
Cy	Ye	Cy	Ye
Mg	G	Mg	G
Cy	Ye	Cy	Ye



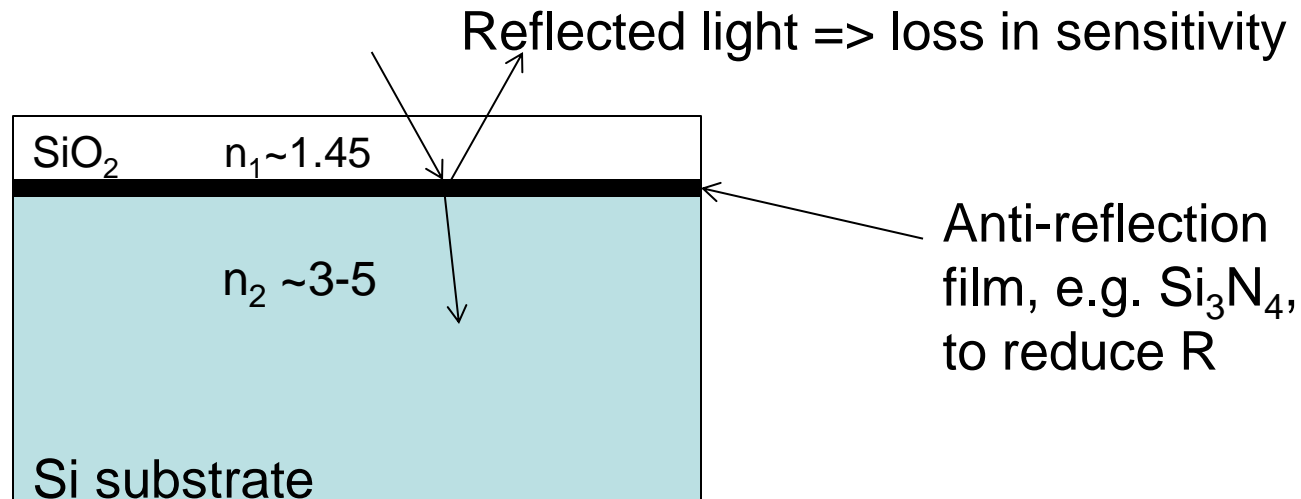
Complimentary CFA

Shading caused by incident light angle



Sensors with pixels $< 2.8\mu\text{m}$ can have different shading curve for R, G, and B. In which case a 3-channel compensation scheme is utilized before color interpolation.

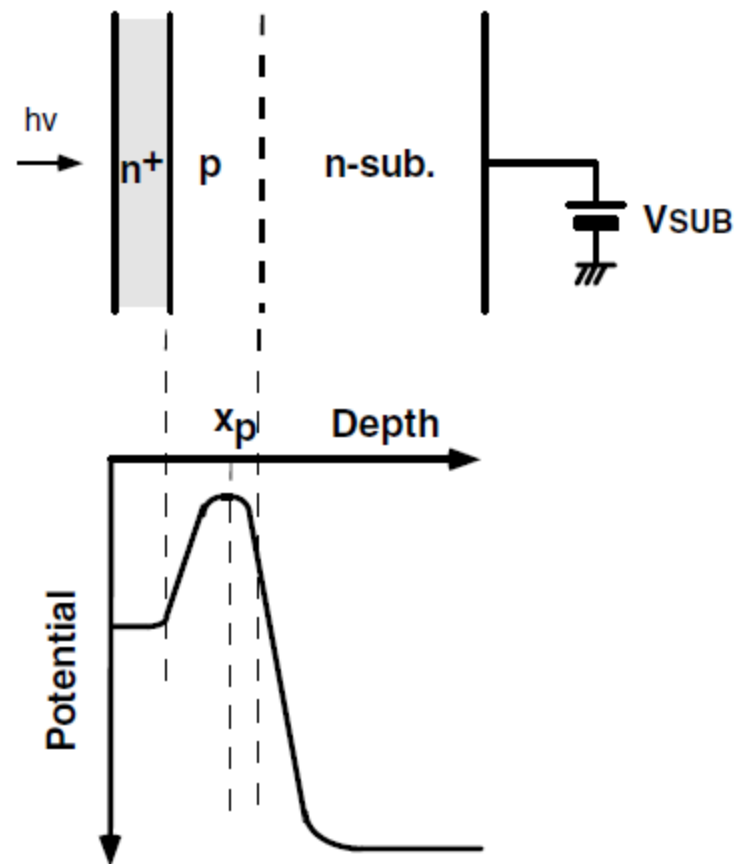
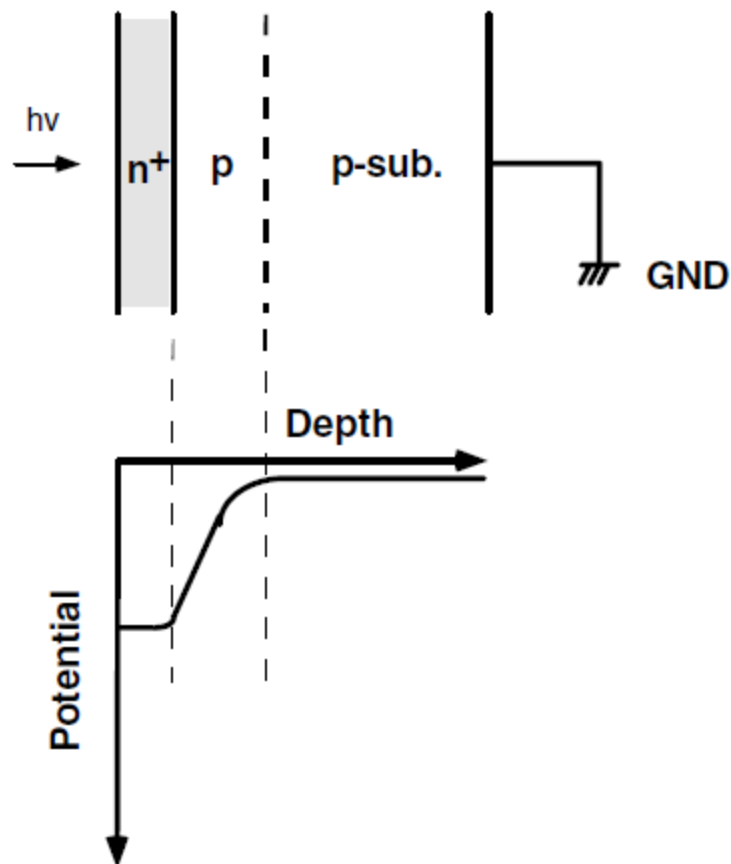
Reflection at the SiO₂/Si interface



For perpendicular light:
$$R = \left(\frac{n_1 - n_2}{n_1 + n_2} \right)^2$$

Anti-reflection coating
reduce the refractive
index deltas at the
interfaces

NP photodiode on p-sub (CIS) vs n-sub (CCD)



Photodiode full well capacity (FWC)

- Maximum number of electrons that can be stored in the pixel
- Sometimes called pixel saturation level

$$N_{sat} = \frac{1}{q} \int_{V_{reset}}^{V_{max}} C_{PD}(V) \cdot dV \quad [\text{electrons}]$$

C_{PD} = photodiode capacitance (F)

V_{reset} = photodiode reset level (V)

V_{max} = photodiode voltage when potential well is filled (V)